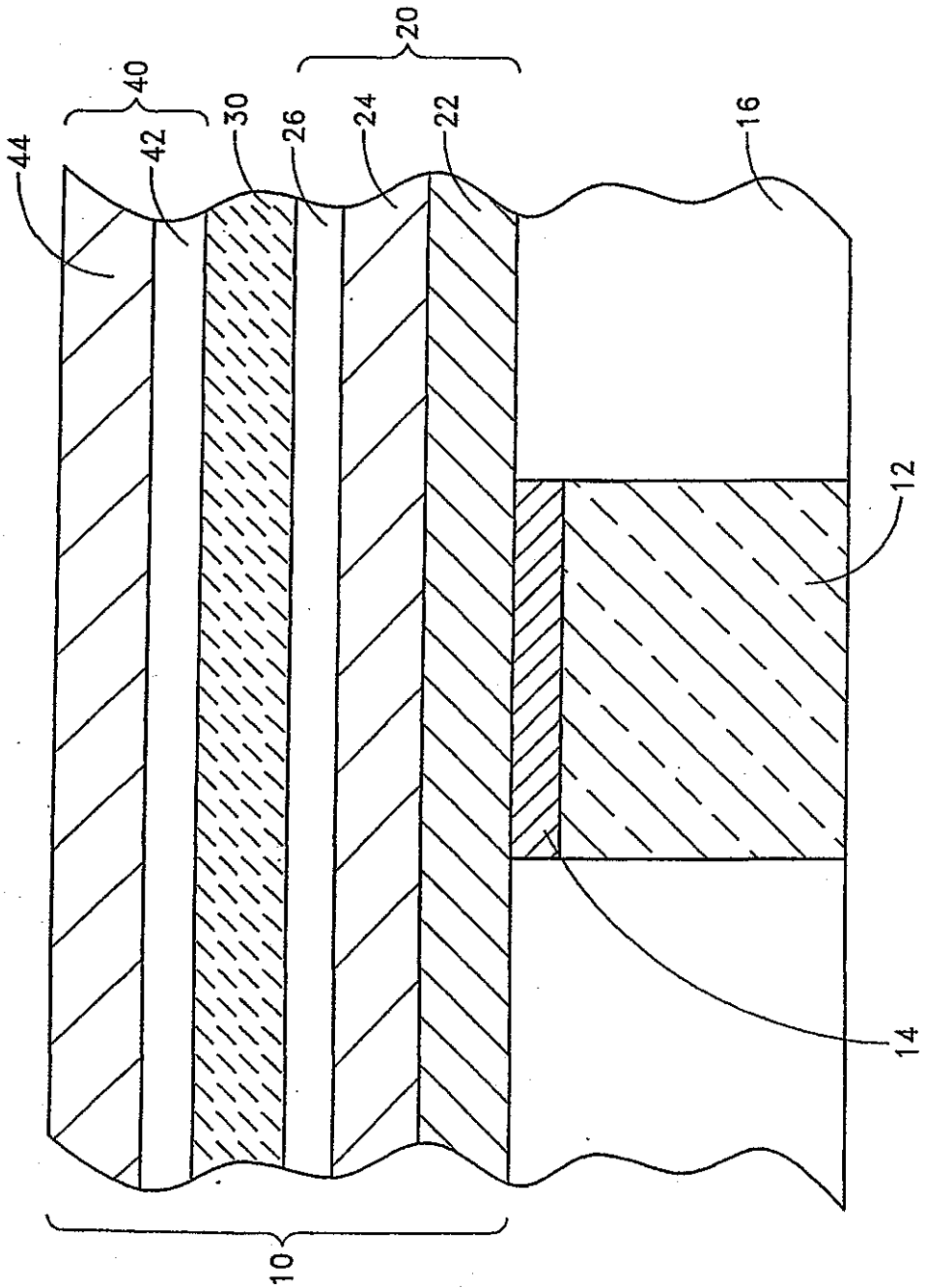


FIG. 1

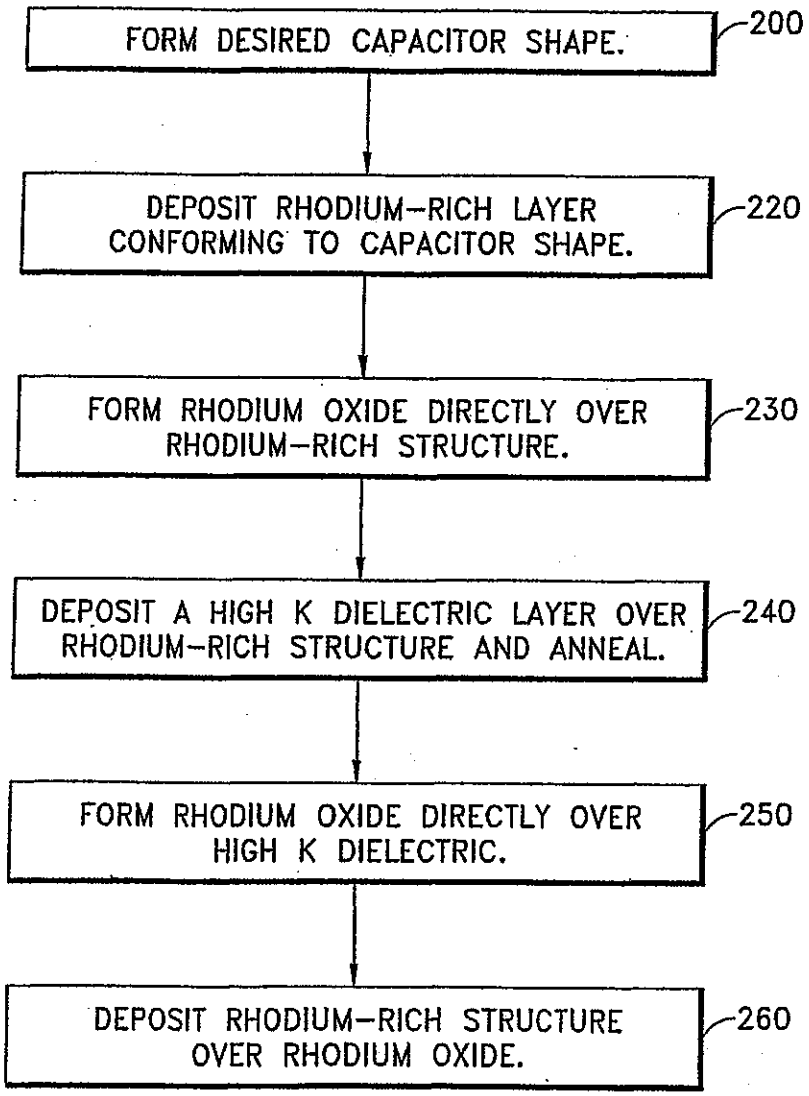

FORM DESIRED CAPACITOR SHAPE.
200
DEPOSIT RHODIUM-RICH LAYER CONFORMING TO CAPACITOR SHAPE.
220
FORM RHODIUM OXIDE DIRECTLY OVER RHODIUM-RICH STRUCTURE.
230
DEPOSIT A HIGH K DIELECTRIC LAYER OVER RHODIUM-RICH STRUCTURE AND ANNEAL.
240
FORM RHODIUM OXIDE DIRECTLY OVER HIGH K DIELECTRIC.
250
DEPOSIT RHODIUM-RICH STRUCTURE OVER RHODIUM OXIDE.
260

FIG. 2

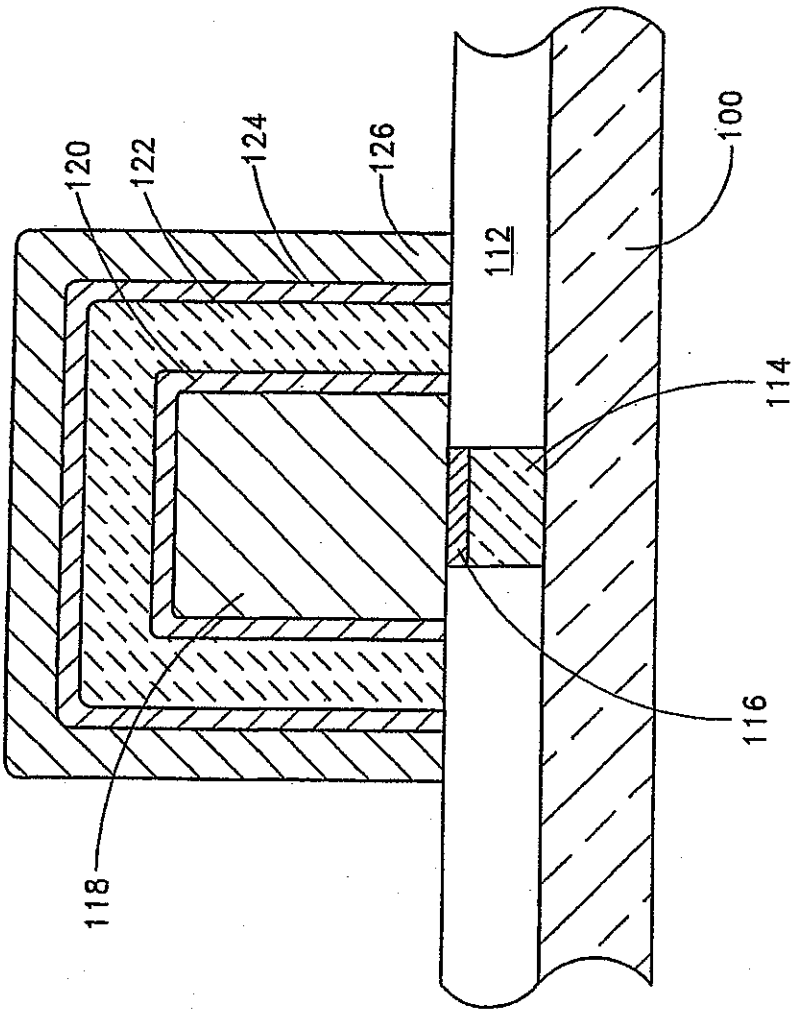


FIG. 3

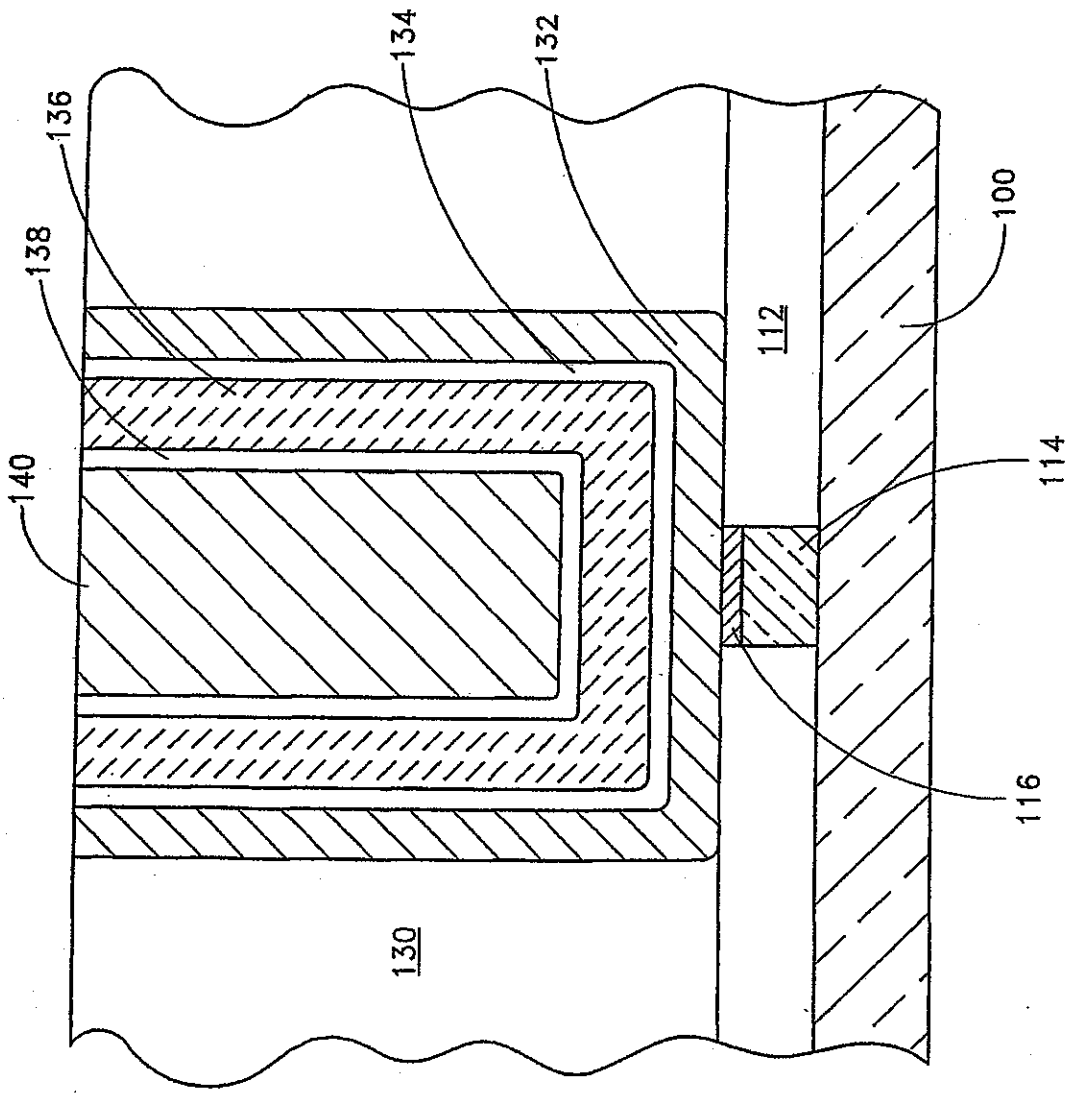


FIG. 4

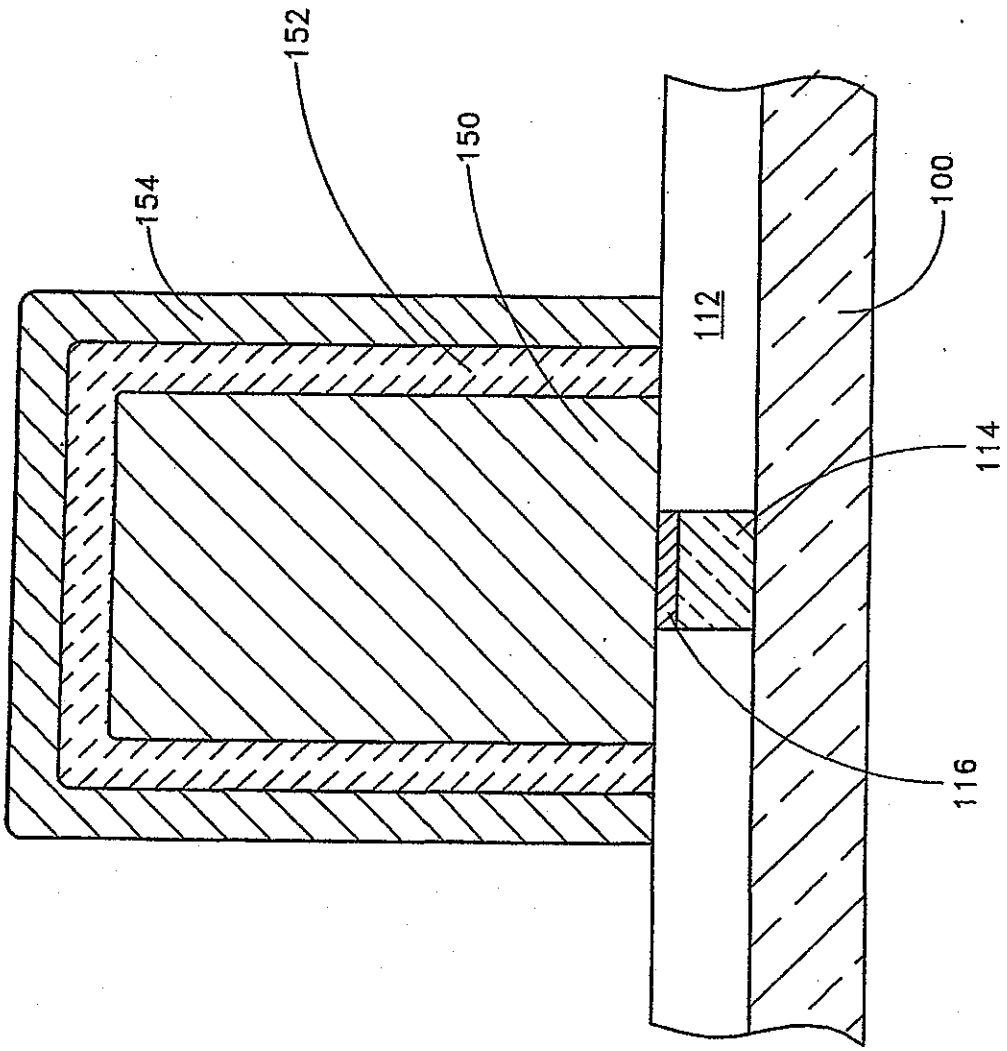


FIG. 5